RESULT LIST

Approximately 136 results found in the Worldwide database for: **piezoelectric ferroelectric layer** in the title or abstract (Results are sorted by date of upload in database)

1 Heterolayered ferroelectric thin films and methods of forming same

Inventor: WANG JOHN (SG); ZHOU ANTHONY Z (SG); Applicant:

(+1)

EC: IPC: B32B9/00

Publication info: US2005128675 - 2005-06-16

2 METHOD OF MANUFACTURING PIEZOELECTRIC DEVICE AND FERROELECTRIC DEVICE, DROPLET DISCHARGING HEAD, AND ELECTRONIC EQUIPMENT

Inventor: TAKAKUWA ATSUSHI; HIGUCHI AMAMITSU; Applicant: SEIKO EPSON CORP

(+1)

EC: IPC: H01L41/22; B41J2/16; (+6)

Publication info: JP2005135973 - 2005-05-26

3 Method of forming piezoelectric layer, heating apparatus used in the same, piezoelectric layer, and piezoelectric element

Inventor: YOKOUCHI TOSHIAKI (JP); SUMI KOJI (JP) Applicant: SEIKO EPSON CORP (JP)

C: IPC: H01L41/04; B32B31/26

Publication info: US2005109456 - 2005-05-26

4 Electronic device and electronic apparatus

Inventor: IWASHITA SETSUYA (JP); HIGUCHI Applicant:

TAKAMITSU (JP); (+1)

EC: H03H9/02S2E IPC: H01G2/00

Publication info: **US2005096230** - 2005-05-05

5 METHOD AND DEVICE FOR ADJUSTING RESONANCE FREQUENCY OF ULTRASONIC SENSOR

Inventor: KITADA KOSAKU; AKETO KOUSHI; (+3)

Applicant: MATSUSHITA ELECTRIC WORKS LTD

EC: IPC: H04R1/22; G01S7/521; (+6)

Publication info: JP2005051685 - 2005-02-24

6 Preparation method of high performance lead zirconium titanate thin

Inventor: CHU JIARU (CN); LU JIAN (CN); (+1)

Applicant: UNIV CHINA SCIENCE & TECH (CN)

EC: IPC: C04B35/49; C04B35/491; (+2)

Publication info: CN1513809 - 2004-07-21

7 ACTUATOR DEVICE, LIQUID JETTING HEAD AND ITS PRODUCTION METHOD, AND LIQUID JETTING DEVICE

Inventor: MURAI MASAMI; MURAMOTO YOSHIYUKI; Applicant: SEIKO EPSON CORP

(+1)

EC: B41J2/14D2; B41J2/16D2; (+6) IPC: B41J2/045; B41J2/055; (+7)

Publication info: JP2005035282 - 2005-02-10

8 Ferroelectric thin film element and its manufacturing method, thin film capacitor and piezoelectric actuator using same

Inventor: KITA HIROYUKI (JP)

Applicant:

EC: H01L21/02B3B2; H01L41/09; (+1) IPC: H01L29/76

Publication info: US2005040454 - 2005-02-24

9 LIQUID INJECTION HEAD, ITS MANUFACTURING METHOD, AND LIQUID INJECTION APPARATUS

Inventor: MURAI MASAMI Applicant: SEIKO EPSON CORP

EC: IPC: B41J2/045; B41J2/055; (+5)

RESULT LIST

Approximately 59 results found in the Worldwide database for: piezoelectric ferroelectric in the title (Results are sorted by date of upload in database)

Ferroelectric film, ferroelectric memory, and piezoelectric element

Inventor: KIJIMA TAKESHI (JP); MIYAZAWA HIROMU Applicant: SEIKO EPSON CORP (JP)

(JP); (+1)

EC: C23C18/12

IPC: H01L29/76

Publication info: US2005167712 - 2005-08-04

FERROELECTRIC FILM, FERROELECTRIC CAPACITOR, FERROELECTRIC MEMORY, PIEZOELECTRIC DEVICE, SEMICONDUCTOR DEVICE, METHOD FOR MANUFACTURING FERROELECTRIC FILM, AND METHOD FOR MANUFACTURING FERROELECTRIC CAPACITOR

Inventor: KIJIMA TAKESHI (JP); HAMADA YASUAKI

Applicant: SEIKO EPSON CORP (JP)

(JP); (+2)

EC: C01G33/00D; C01G35/00D; (+9)

IPC: H01B3/12; C01G25/00; (+3)

Publication info: EP1555678 - 2005-07-20

METHOD OF FORMING ELECTRODE, PIEZOELECTRIC DEVICE, FERROELECTRIC DEVICE, AND ELECTRONIC EQUIPMENT

Inventor: TAKAKUWA ATSUSHI; HIGUCHI AMAMITSU; Applicant: SEIKO EPSON CORP

(+1)

EC:

IPC: H01L21/288; H01L21/28; (+8)

Publication info: JP2005135975 - 2005-05-26

METHOD OF FORMING INSULATING FILM, PIEZOELECTRIC DEVICE, FERROELECTRIC DEVICE, AND ELECTRONIC EQUIPMENT

Inventor: TAKAKUWA ATSUSHI; HIGUCHI AMAMITSU; Applicant: SEIKO EPSON CORP

(+1)EC:

IPC: H01L21/316; H01L27/105; (+6)

Publication info: JP2005135974 - 2005-05-26

METHOD OF MANUFACTURING PIEZOELECTRIC DEVICE AND FERROELECTRIC DEVICE, DROPLET DISCHARGING HEAD, AND **ELECTRONIC EQUIPMENT**

Inventor: TAKAKUWA ATSUSHI; HIGUCHI AMAMITSU; Applicant: SEIKO EPSON CORP

(+1)EC:

IPC: H01L41/22; B41J2/16; (+6)

Publication info: JP2005135973 - 2005-05-26

Piezoelectric device, liquid jetting head, ferroelectric device, electronic device and methods for manufacturing these devices

Inventor: HIGUCHI TAKAMITSU (JP); IWASHITA

Applicant: SEIKO EPSON CORP

SETSUYA (JP); (+5)

EC:

IPC: H01L41/047

Publication info: US2005122005 - 2005-06-09

FERROELECTRIC FILM, FERROELECTRIC MEMORY, PIEZOELECTRIC ELEMENT, SEMICONDUCTOR ELEMENT, LIQUID EJECTION HEAD, PRINTER AND PROCESS FOR PRODUCING FERROELECTRIC FILM

Inventor: KIJIMA TAKESHI; HAMADA YASUAKI; (+1) Applicant: SEIKO EPSON CORP

EC: IPC: H01L27/105; B05C5/00; (+8)

Publication info: JP2005101512 - 2005-04-14

FERROELECTRIC THIN FILM AND ITS PRODUCING PROCESS. FERROELECTRIC MEMORY, PIEZOELECTRIC ELEMENT

Inventor: KIJIMA TAKESHI; MIYAZAWA HIROSHI; (+2) Applicant: SEIKO EPSON CORP

EC: C23C30/00; H01L21/316D; (+1) IPC: H01L27/105; B41J2/045; (+13)

[Search Summary]

Results of searching in PCT for:

piezoelectric near layer and ferroelectric near layer: 1 record

Showing record 1 to 1 of 1:

Refine Search

piezoelectric near layer and ferroelectric near layer

Score Title

1. (100) (WO 99/48083) INERTIAL/AUDIO UNIT AND CONSTRUCTION

Search Summary

piezoelectric NEAR layer: 408 occurrences in 211 records. piezoelectric NEAR layer: 408 occurrences in 211 records.

(piezoelectric NEAR layer AND piezoelectric NEAR layer): 211 records.

ferroelectric NEAR layer: 288 occurrences in 145 records.

((piezoelectric NEAR layer AND piezoelectric NEAR layer) AND ferroelectric NEAR

layer): 1 record.

Search Time: 0.95 seconds.

http://www.wipo.int/cgi-pct/guest/ilist5?ENG+PCT-ALL.vdb+14+1147394-SCORE+1+BAS... 9/23/05



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1	BRS	L1		О	"2362989".fref.	USPAT	2005/09/2 3 12:00	
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3	BRS	L3		0	"2362989".frpn.	; EPO; JPO; DERWE NT; IBM_T DB	2005/09/2 3 12:01	
4	BRS	L4		0	"2362989".fref.	US- PGPUB; USPAT; USOCR; EPO; JPO; DERWE NT; IBM_T DB	2005/09/2 3 12:01	
5	IS&R	L5	·	2813	(310/317,328,330,358). CCLS.	USPAT	2005/09/2 3 12:03	
6	BRS	L6		143	ferroelectric adj2 material\$1 adj2 including	USPAT	2005/09/2 3 12:10	
7	BRS	L7	٠	9	"ferroelectric layer" same "piezoelectric layer"	USPAT	2005/09/2 3 12:13	

	Туре	L #	Hits	Search Text	DBs	Time Stamp	Comment 's
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